

Germanium Detectors in Positron Annihilation Spectroscopy Experiments

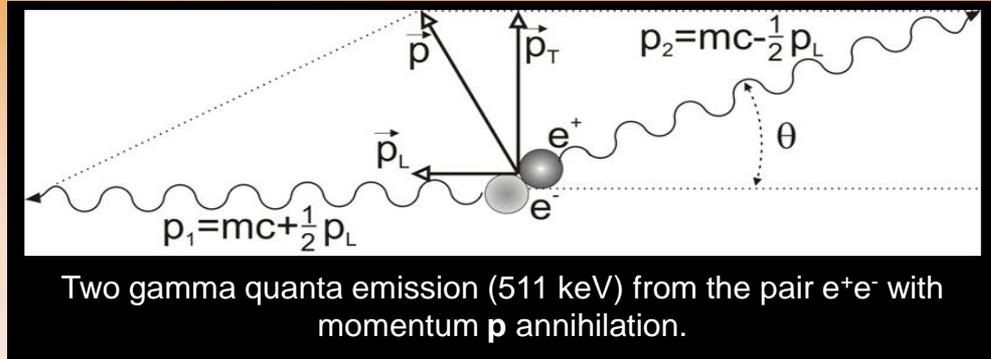
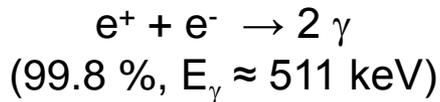
Pawel Horodek

Outline:

- Basics of PAS
- DBGL technique
 - spectrometer
 - analysis of annihilation line
- Example of application
- Summary

Basics of PAS

ANNIHILATION e^+e^-



POSITRON SOURCES

β^+ decay isotopes
 $p^+ = n + e^+ + \nu_e$

| Isotope | $T_{1/2}$ | Positron energy [MeV] |
|------------------|------------|-----------------------|
| ^{11}C | 20 min. | 0.96 |
| ^{13}N | 9.96 min. | 1.20 |
| ^{15}O | 2.05 min. | 1.74 |
| ^{18}F | 1.83 hours | 0.64 |
| ^{22}Na | 2.62 years | 0.55 |
| ^{44}Ti | 47 years | 1.47 |
| ^{58}Co | 71.3 days | 0.48 |
| ^{64}Cu | 12.8 hours | 0.66 |
| ^{68}Ge | 275 days | 1.88 |

Examples of β^+ decay isotopes

INTERACTION

- elastic scattering
- nonelastic scattering
- bremsstrahlung

INSIDE THE MATTER

- implantation into medium
- thermalization
- diffusion
- annihilation with electron

THE DEVIATION FROM COLINEARITY

$$\theta = \frac{p_\perp}{mc}$$

CHANGING OF GAMMA QUANTA ENERGY as a result of the Doppler shift

$$E_\gamma \cong m \cdot c^2 + E_B \pm \frac{p_\parallel \cdot c}{2}$$

Basics of PAS

EXPERIMENTAL TECHNIQUES

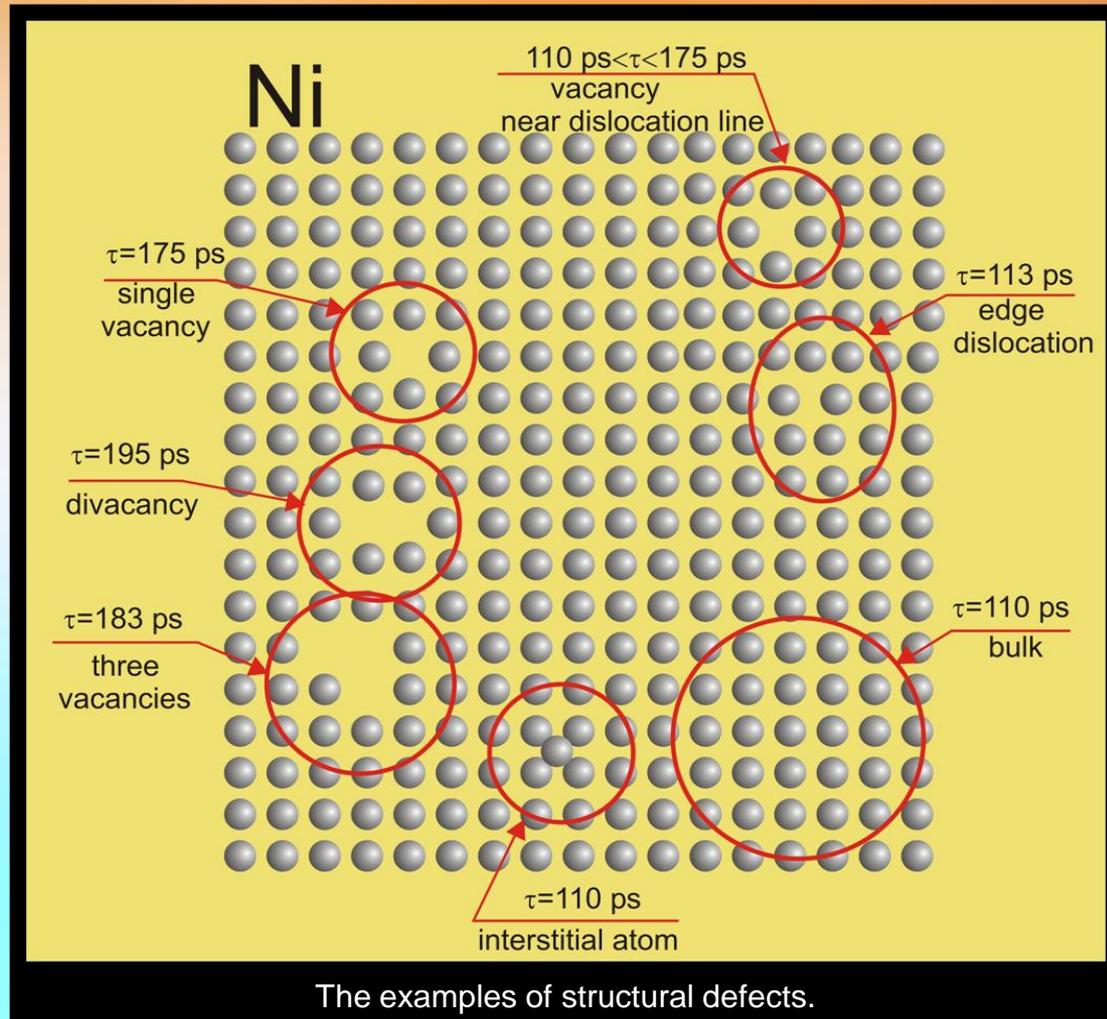
- Doppler broadening of annihilation gamma line (DBGL)
- positron life times (LT)

POSSIBILITIES

- defect concentration
- defect concentration profile
- detection of the kind and size of defects

APPLICATIONS

- solid body physics
- material and surface engineering
- metals, semiconductors, thin layers



DBGL technique

gamma ≈ 511 keV

HpGe detector

preamplifier

amplifier

MC analyzer

PC computer



The energy resolution of DBGL spectrometer at LEPTA project is 1.2 keV interpolated at 511 keV.

DBGL technique

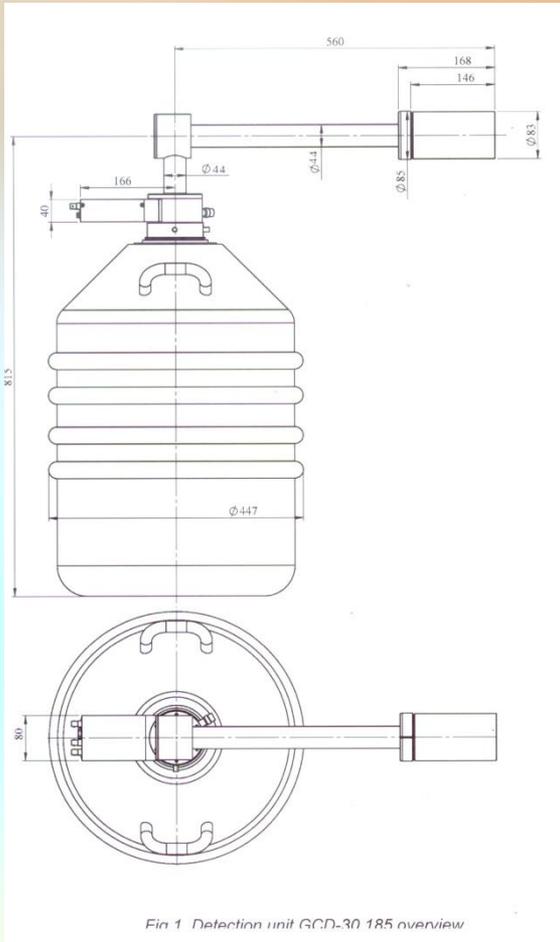
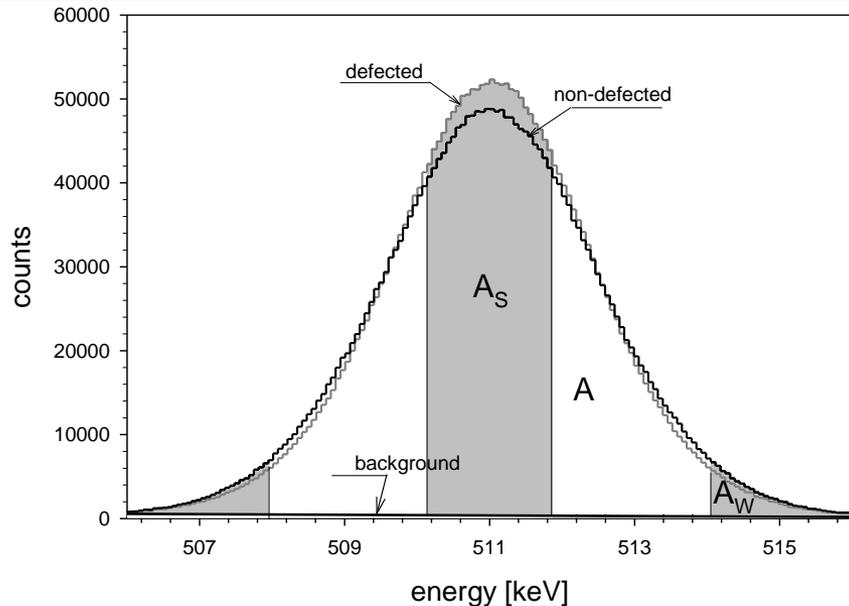


Fig 1. Detection unit GCD-30.185 overview

| Parameter Name | Value |
|--|-----------------|
| 1. Gamma – ray energy range, keV | 40 - 10000 |
| 2. Energy resolution for energies, eV: | |
| 122 keV | 834 |
| 511 keV | 1210 |
| 1332 keV | 1787 |
| * total system resolution for a source at 1000 counts/s measured in accordance with ANSI/IEEE Std. 325-1996, using spectrum analyzer Multispectrum Hibrid, BSI Ltd. | |
| 3. Relative efficiency for energies 1,33 MeV to (NaI)Ti, % | 30.0 |
| Peak/Compton ratio: | 58:1 |
| 4. Optimal shaping time, μ s | 6 |
| 5. Optimal operating voltage, V, plus | 4600 |
| 6. Sensitive area: | |
| diameter, mm | 57.4 |
| depth, mm | 57.45 |
| 7. Al end cap thickness, mm | 0.7 |
| 8. Spacing between detector face and end cap window, mm | 8 |
| 9. Cooling | LN ₂ |

DBGL technique



Comparison of annihilation lines for defected and nondefected samples. The rule of calculation of S- and W-parameters.

S - parameter

- relation of area under the central part of annihilation line to whole area below this line

$$S = \frac{A_S}{A}$$

- defines the participation of pairs positron-electron with low momentum
- the bigger value the bigger concentration of such defects as vacancies

W - parameter

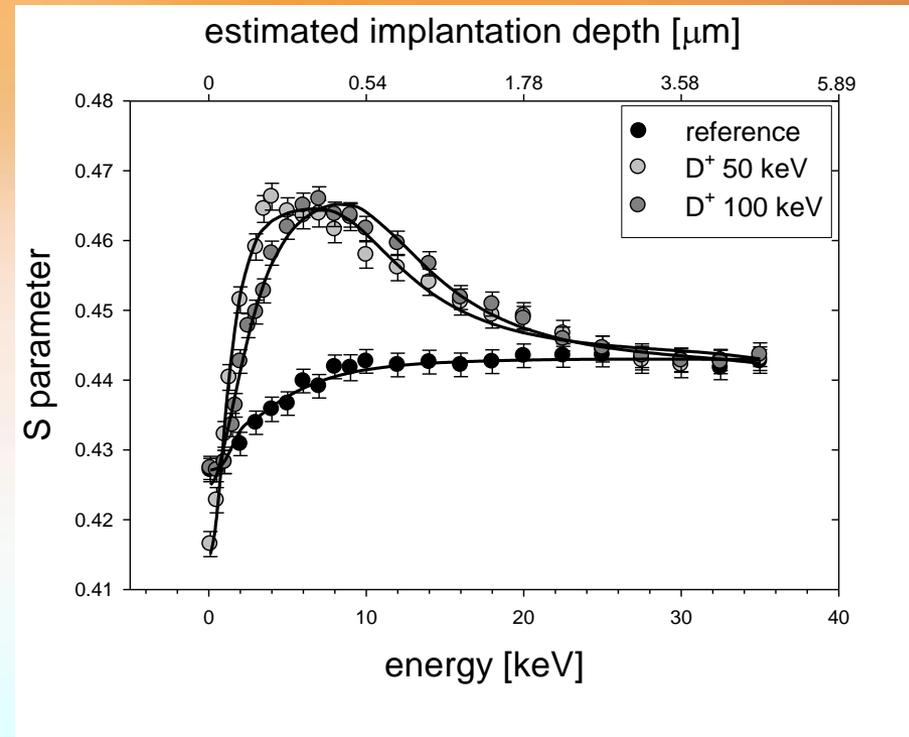
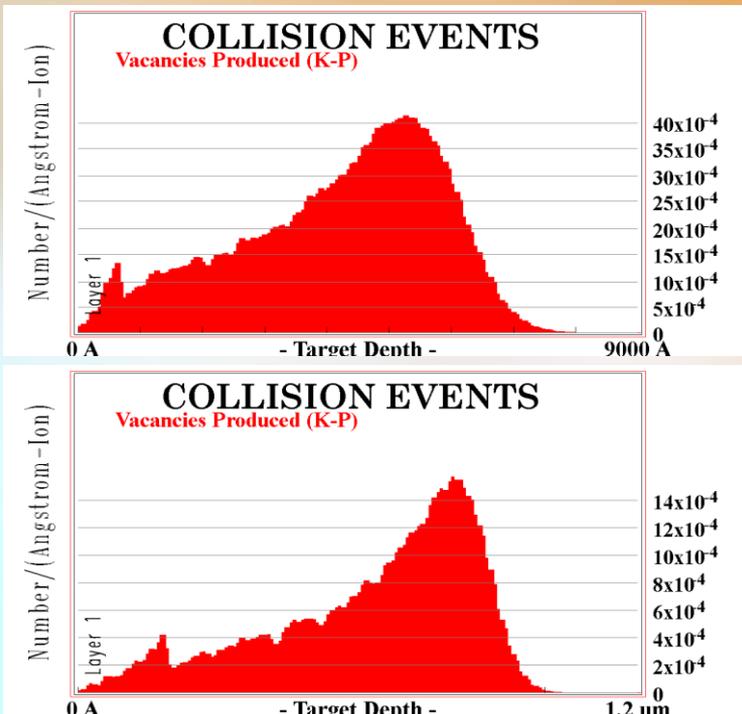
- defines the participation of pairs positron-electron with high momentum

$$W = \frac{A_W}{A}$$

- together with S- parameter gives information about kinds of defects

At the beginning of the measurement session ΔE intervals are chosen to have about **0.5 for S- parameter** and lower than **0.01 for W- parameter**

Example of application



OBJECTS:

- ✓ Si (1,0,0) samples after deuterium implantation
- ✓ the fluence of D⁺ beam: 6×10^{16} at/cm²
- ✓ energy of D⁺ beam: 50, 100 keV

THE DIFFUSION EQUATION

$$S(E) = S_{zone} + (S_{surface} - S_{zone}) \times \int_0^{\infty} P(x, E) \exp\left(-\frac{x}{L_+}\right) dx$$

- ✓ VEPFIT program solves it to fit the model function to experimental data

Example of application

THE DEFECT CONCENTRATION

$$C = \left[\left(\frac{L_{bulk}}{L_+} \right)^2 - 1 \right] / (\tau_{bulk} \mu)$$

where τ_{bulk} is 109.6 ps, μ is the trapping coefficient for divacancies in pure Si equal $8 \times 10^{14} \text{ s}^{-1}$, L_{bulk} is 218 nm (the positron diffusion length) in the bulk)

| Sample | L_+ [nm] | Thickness [nm] | C_{2V} |
|-----------|------------|----------------|--------------------------------------|
| reference | 220 (13) | - | - |
| 50 keV | 43 (1) | 571 (18) | $7.2 \times 10^{18} \text{ cm}^{-3}$ |
| 100 keV | 50 (1) | 877 (27) | $5.3 \times 10^{18} \text{ cm}^{-3}$ |

It is usual to calculate the defect concentration of open volume defects (up to small vacancy cluster) with the positron trapping coefficient for divacancies $\mu_{2V} = 8 \times 10^{14} \text{ s}^{-1}$. For comparison in the samples of Si multiimplanted with B ions with energies 50, 100 and 150 keV the concentration of divacancies observed by infrared absorption spectroscopy (IRAS) was ca. $1.8 \times 10^{19} \text{ cm}^{-3}$. [Borner et.al, Phys. Rev. B 56 1997, 1393]

□ Summary

- PAS is the sensitive method for detection the structural defects
- It does not need advanced detectors for measuring the annihilation characteristics
- HpGe detectors offered by many companies are fully available and they are not connected with high costs in comparison to huge experiments

**Thank you for
your attention !!!**